

2/25/03 SBG

L Number	Hits	Search Text	DB	Time stamp
1	23373	269/\$ ccls.	USPAT	2003/08/25 00:33
2	1015	269/\$ ccls. and (station or stations)	USPAT	2003/08/25 00:19
3	291	(269/\$ ccls. and (station or stations)) and recess	USPAT	2003/08/25 00:19
4	136	((269/\$ ccls. and (station or stations)) and recess) and arm	USPAT	2003/08/25 00:46
5	104	(269/\$ ccls. and (station or stations)) and ((station or stations) with (wheel or wheels or disc or discs or circle or circles or round or circular or spin))	USPAT	2003/08/25 00:22
6	15	269/\$ ccls. and (flexible adj arm)	USPAT	2003/08/25 00:45
7	4	269/\$ ccls. and (fluoropolymer)	USPAT	2003/08/25 00:46
8	181	269/\$ ccls. and teflon	USPAT	2003/08/25 00:46
9	3	((269/\$ ccls. and (station or stations)) and recess) and arm) and teflon	USPAT	2003/08/25 00:55
12	1	("3647043").PN.	USPAT	2003/08/25 00:56
14	23	269/\$ ccls and ((retaining adj arm) or (retain adj arm) or (retainer adj arm))	USPAT	2003/08/25 00:59
15	2308	((retaining adj arm) or (retain adj arm) or (retainer adj arm))	USPAT	2003/08/25 00:59
16	24	((retaining adj arm) or (retain adj arm) or (retainer adj arm))) and (wafer)	USPAT	2003/08/25 00:59
-	65	((((article and (station or stations)) and ((MEMS adj die) or (MEMS) or (die))) and apparatus) and (tool or arm)) and (teflon)	USPAT	2003/08/22 18:33
-	13	MEMS adj die	USPAT	2002/11/26 23:34
-	288	438/\$ ccls and MEMS	USPAT	2002/11/26 23:35
-	351	438/\$ ccls and (MEMS or (microelectromechanical))	USPAT	2002/11/27 00:54
-	94	29/603.17 or 29/603.19	USPAT	2002/11/26 23:53
-	59	29/603.17 ccls. or 29/603.19 ccls.	USPAT	2002/11/26 23:53
-	39	29/650 ccls.	USPAT	2002/11/26 23:55
-	824	269/55 ccls. or 269/56 ccls. or 269/57 ccls.	USPAT	2002/11/27 00:25
-	3	269/\$ ccls and mems	USPAT	2002/11/27 00:25
-	3	269/\$ ccls and (micromechanical)	USPAT	2002/11/27 00:26
-	562	269/\$ ccls and semiconductor	USPAT	2002/11/27 00:44
-	131	257/\$ ccls and MEMS	USPAT	2002/11/27 00:58
-	705	438/455 ccls. or 438/456 ccls. or 438/458 ccls.	USPAT	2002/11/27 01:08
-	27	(438/455 ccls. or 438/456 ccls. or 438/458 ccls.) and teflon	USPAT	2002/11/27 01:09
-	1	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and MEMS	USPAT	2003/05/08 13:17
-	1561	414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.	USPAT	2003/05/08 13:25
-	0	269/\$ ccls and (MEMS adj die)	USPAT	2003/05/08 13:23
-	578	269/\$ ccls and (semiconductor)	USPAT	2003/05/08 13:21
-	0	269/\$ ccls and (micro adj electro adj mechanical adj die)	USPAT	2003/05/08 13:21
-	1	269/\$ ccls and (micro adj electro adj mechanical)	USPAT	2003/05/08 13:23
-	0	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and (MEMS adj die)	USPAT	2003/05/08 13:23
-	1	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and (MEMS)	USPAT	2003/05/08 13:23
-	0	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and (micro adj electro adj mechanical)	USPAT	2003/05/08 13:23
-	0	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and (microelectromechanical-systems)	USPAT	2003/05/08 13:23
-	258	(414/935 ccls. or 414/936 ccls. or 414/937 ccls. or 414/938 ccls. or 414/939 ccls. or 414/940 ccls. or 414/941 ccls.) and (microelectromechanical-systems)	USPAT	2003/05/08 13:26
-	0	269/55 ccls	USPAT	2003/08/22 18:16
-	0	station and recess and (flexible adj retaining adj arm)	USPAT	2003/08/22 18:17
-	0	flexible adj retaining adj arm	USPAT	2003/08/22 18:17
-	27	flexible adj retaining adj arm	USPAT	2003/08/22 18:31